

# Particle Distribution Analysis of Electron Microscopy images using deep learning in material science.

## Abstract

This research aims to develop an automated deep learningbased methodology for particle segmentation and counting in electron microscopy (EM) images, which are widely used in material science for understanding particle distribution. Traditional manual analysis methods are time-consuming and prone to subjectivity. To overcome these challenges, we applied the DeepLabV3 architecture, pretrained on ResNet-50, to segment particles with high precision. The dataset consists of 465 electron microscopy images with pixel-level segmentation. By incorporating data preprocessing techniques, such as augmentation and normalization, and postprocessing steps like thresholding and connected component labeling, we enhanced segmentation quality and particle counting accuracy. The results demonstrate the model's capability to automate and improve particle distribution analysis, offering significant advantages over manual methods.

## Introduction

•Particle distribution analysis in material science refers to the process of characterizing and understanding the arrangement, size, shape, and spatial distribution of particles within a material or sample.

•EM(Electron microscopy) images are pictures taken using electron microscopes.



## Objective

Original image







Output particle segmentation, Count particles

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## Dataset

The dataset used for this research, "Electron Microscopy **Particle Segmentation**<sup>"</sup>[1], was obtained from Kaggle. It includes 465 electron microscopy images along with their corresponding pixel-level segmentations.

#### **Annotate Segmentation Maps**

Annotate segmentation maps to label particles and their borders using morphological operations.

#### Value Labels:

- 0: Background region
- 1: Particle region
- 2: Border of the particle



## Methodology



#### **Step 1. Image Preprocessing**

#### Image Augmentation

Image Transformations:

- ➢ Resize
- ➢ Flipping
- Random Cropping
- ➢ Random Rotations

Color Augmentations:

- Brightness and Contrast Adjustments
- ➢ Gamma Adjustments

- Distortion Techniques:
- Elastic Transform
- Grid Distortion
- Optical Distortion

### Normalization

### **Step 02. Model Training**

#### **1. Model Architecture:**



## **Step 04.Postprocessing**



The accuracy values range from around 0.58 to 0.98 across different images. **IoU scores** range from approximately 0.30 to 0.89. Dice scores range from about 0.44 to 0.93

Images normalized using mean (0.4773) and standard deviation (0.1719)

Utilize the DeepLabV3 architecture with a modified classifier for 3 output classes.

Pretrained on ResNet-50 for feature extraction.

#### **2.** Loss Function and Optimization:

Use weighted cross-entropy loss to handle class imbalance.

Adam optimizer with an initial learning rate of 1e-3.

Cosine annealing scheduler for dynamic learning rate adjustments.

#### 3. Training Setup:

Number of Epochs:50 epochs

Batch Size:8

#### **Step 03.Particle Semantic Segmentation**



Convert border pixels to background Threshold the image to create a binary image Label connected components in the binary image







## Result

#### Easy Case



[Above 3 images, the model accurately segmented wellseparated particles with regular shapes and sizes, demonstrating strong boundary detection]

#### **Difficult Case**



Figure1

[ Figure1-The model merged overlapping particles into a single entity, resulting in under-segmentation.Figure2-Small particles near the resolution limit were frequently missed or misclassified as background.Figure3- In highdensity regions, where many particles are packed closely together, the model has difficulty identifying and separating each particle ]

- images.







## Conclusion

Our customized DeepLabV3 model effectively recognizes nanoparticles in electron microscopy

We recommend exploring other deep learning models and combining this dataset with additional data for further improvements.

## References

1. Yildirim, Batuhan, and Jacqueline M. Cole. "Bayesian particle instance segmentation for electron microscopy image quantification." Journal of Chemical Information and Modeling 61.3 (2021): 1136-1149..

2. Liz, Mikhail F., et al. "Using computer vision and deep learning" for nanoparticle recognition on scanning probe microscopy images: modified U-net approach." 2020 Science and Artificial Intelligence conference (SAI ence). IEEE, 2020.

3. Horwath, James P., et al. "Understanding important features of deep learning models for segmentation of high-resolution transmission electron microscopy images." npj Computational Materials 6.1 (2020): 108.